

Microstereolithography and other Fabrication Techniques for 3D MEMS

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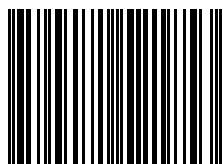
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The application of MEMS (micro-electro-mechanical systems) in such diverse fields as intelligent microsensors, data storage, biomedical engineering and wireless communications is booming. Focusing on microstereolithography, this timely work provides insight into state-of-the-art microfabrication techniques for 3D microstructures, microdevices and MEMS.

- A unique and accessible overview of micro-system manufacture using the latest semiconductor processing techniques.
- Coverage of the developmental history of MEMS, micro-sensors, actuators and signal processing units.
- Insight to a range of microfabrication techniques from laser ablation to x-ray lithography, silicon micro-machining and micro-moulding.
- Describes the latest fabrication prototypes and applications, including thin-film transistors, antennas, wireless telemetry systems and transducers.

Microelectronics engineers will profit from this detailed overview of current technologies. Material technologists and physicists working in industrial and academic research and development will also find this a valuable reference source.

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Cover illustration: SEM photographs of structures made by microstereolithography. Source: Arnaud Bertsch, EPFL, Switzerland. Reproduced with permission.

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